

PROBE SYSTEM FOR LIFE



M12 – 300 mm Manual Probe System

The SemiProbe M12 is the most modular and flexible 300 mm manual probe system available today. It is built using our patented Probe System for Life (PS4L) architecture which provides unsurpassed flexibility and significant capital equipment savings. With the PS4L, customers can purchase a manual 300 mm system that meets their precise specifications and requirements.

The Probe System for Life (PS4L) family of wafer probing systems is designed based on SemiProbe's patented adaptive architecture. Unlike traditional probe systems, all foundation modules – bases, stages, chucks, microscope mounts, microscope movements, optics, manipulators and more - are interchangeable, making the PS4L the consummate solution for many different applications and budgets. This unique modular design enables customers to acquire test capabilities that precisely match their requirements. More important, as the environment or test conditions change, the PS4L can easily be field-upgraded to meet these new demands. With this design philosophy, PS4L customers realize substantial time and cost savings over traditional probe systems because they do not need to invest in a new platform when wafer size, levels of automation or test requirements change.



M12 manual probe system configured above with a Rapid Advance wafer chuck, 300 mm chuck, fixed platen, DC manipulators, compound optics, CCTV system, test instrumentation mounted on a vibration isolation table - several configurations available.

A complete line of accessories is available for all systems including probe card holders, manipulators, probe arms & bases, probe tips, thermal chucks, environmental chambers, lasers, optics, CCTV systems, vibration isolation tables, dark boxes and more.

FEATURES AND BENEFITS

- 300 mm manual system with upgrade path to 300 mm semiautomatic system
- All key components are interchangeable which enables the system to easily be configured to meet applications and budgets – present and future
- Software and hardware modules provide a perpetual field upgrade path

Major Applications/Markets Served

Device Characterization, MEMS, Optoelectronics, HF/Microwave, High Power, Photovoltaic, Failure Analysis, Research, Material Science and more

SPECIFICATIONS

Dimensions	1200 mm x 650 mm x 900 mm (47.3" x 25.4" x 35.5") (W,H,L) - with optics
Weight	110 Kg (245 lbs.)
Chuck Stage X-Y Movement	Rapid align with coarse and fine stage movements - coarse >300 mm, fine is 25 mm (X, Y) Travel: Fine X, Y stage movement of 25 mm via precision micrometers Planarity: +/- 7.5 µm over travel range Resolution: 5 µm Stage Types: Rapid Align (standard), coaxial and programmable (optional)
Chuck Stage Z Movement	Z Travel: >20 mm with precision micrometer
Theta Movement	Travel: Coarse (360 degrees) and fine (>10 degrees) with theta locking knob
Chucks	Vacuum or mechanical clamping, round or square, triaxial, HF, HV/HC, ambient, thermal and custom Handle die, wafer packs, sawn wafers on frame, broken wafers and full wafers up to 300 mm Nickel plated steel with concentric vacuum rings (standard), other plating materials available Planarity: 5 µm
Platen:	Aluminum with stainless steel top with removable front wedge 360 degree manipulator placement Manipulator fixation – magnetic (standard), vacuum (optional with vacuum manifold kit)
Platen Movement	Platen Lift: Choice of fixed or adjustable (linear) Adjustable: Coarse - 40 mm, Fine – 200 um contact/separation stroke via lever - lockable
Microscope Mounting/Movement	Mounting – Boom, Post or Bridge Movement – Manual or Programmable – 50 x 50 mm, 50 x 75 mm, 100 x 100 mm and 200 x 200 mm
Microscope (Optics)	Stereo Zoom, Zoom Tube, A-Zoom or Compound Microscope
Utilities	Power: AC 110/220V AC 50-60 Hz 20A Vacuum: 23 Hg or -0.8 bar

Note: Data and specifications vary depending on probe system configurations and accessories

PHYSICAL DIMENSIONS

